

SLOVENSKI STANDARD SIST EN IEC 63373:2022

01-maj-2022

Smernice za dinamične metode preskusov odpornosti za naprave za pretvorbo energije na osnovi GaN HEMT (IEC 63373:2022)

Dynamic on-resistance test method guidelines for GaN HEMT based power conversion devices (IEC 63373:2022)

Richtlinien für Prüfverfahren des dynamischen Einschaltwiderstandes bei GaN-HEMT-Leistungswandlern (IEC 63373:2022)

PREVIEW

Lignes directrices pour les méthodes d'essai de résistance dynamique à l'état passant des dispositifs de conversion de puissance fondés sur les HEMT en GaN (IEC 63373:2022)

SIST EN IEC 63373:2022

Ta slovenski standard je istoveten z:ai/cat**ENgEC 63373:2022** af23d-7f15-4b7f-9080-8479a3e3712c/sist-en-iec-63373-2022

ICS:

31.080.99 Drugi polprevodniški elementi Other semiconductor devices

SIST EN IEC 63373:2022

en



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SIST EN IEC 63373:2022

EUROPEAN STANDARD NORME EUROPÉENNE EUROPÄISCHE NORM

EN IEC 63373

March 2022

ICS 31.080.99

English Version

Dynamic on-resistance test method guidelines for GaN HEMT based power conversion devices (IEC 63373:2022)

Lignes directrices pour les méthodes d'essai de résistance dynamique à l'état passant des dispositifs de conversion de puissance fondés sur les HEMT en GaN (IEC 63373:2022) Richtlinien für Prüfverfahren des dynamischen Einschaltwiderstandes bei GaN-HEMT-Leistungswandlern (IEC 63373:2022)

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European Committee for Electrotechnical Standardization Comité Européen de Normalisation Electrotechnique Europäisches Komitee für Elektrotechnische Normung

CEN-CENELEC Management Centre: Rue de la Science 23, B-1040 Brussels

EN IEC 63373:2022 (E)

European foreword

The text of document 47/2690/CDV, future edition 1 of IEC 63373, prepared by IEC/TC 47 "Semiconductor devices" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN IEC 63373:2022.

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Edition 1.0 2022-02

INTERNATIONAL STANDARD

NORME INTERNATIONALE



iTeh STANDARD

Dynamic on-resistance test method guidelines for GaN HEMT based power conversion devices

Lignes directrices pour les méthodes d'essai de résistance dynamique à l'état passant des dispositifs de conversion de puissance fondés sur les HEMT en GaN

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

COMMISSION ELECTROTECHNIQUE INTERNATIONALE

ICS 31.080.99

ISBN 978-2-8322-1076-6

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DYNAMIC ON-RESISTANCE TEST METHOD GUIDELINES FOR GaN HEMT BASED POWER CONVERSION DEVICES

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Draft	Report on voting
47/2690/CDV	47/2735/RVC

Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this International Standard is English.

¹ Numbers in square brackets refer to the Bibliography.

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INTRODUCTION

This document is intended for use in the GaN power semiconductor and related power electronic industries, and provides guidelines for measuring the dynamic ON-resistance of GaN power devices.

Gallium Nitride (GaN) lateral power High Electron Mobility Transistor (HEMT) conducts through a two-dimensional electron gas (2DEG) in ON-state operation. Due to the various stress conditions that the device encounters during power electronic switching applications, some charge could get trapped in specific regions of the transistor structure. The trapped electrons cause an increased ON-resistance when operated in a switching environment. This phenomenon is known as current collapse and the ON-resistance at switching operation is called dynamic ON-resistance in order to distinguish from DC ON-resistance. Increased dynamic ON-resistance translates to higher power loss, thereby reducing overall system efficiency. Not verifying the dynamic ON-resistance characteristic can put GaN device reliability at risk [2].

The test methods provided in this document can be used as a guideline for measuring dynamic ON-resistance of GaN power device, focused on lateral HEMT technologies. These three test methods can be applied for datasheet, process control, technology development, final tests and other usage. Parasitic effects impact high precision measurements and wafer level tests can minimize parasitic effects. Additionally, self-heating can impact the package level tests depending upon the package thermal characteristics

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DYNAMIC ON-RESISTANCE TEST METHOD GUIDELINES FOR GaN HEMT BASED POWER CONVERSION DEVICES

1 Scope

In general, dynamic ON-resistance testing is a measure of charge trapping phenomena in GaN power transistors. This publication provides guidelines for testing dynamic ON-resistance of GaN lateral power transistor solutions. The test methods can be applied to the following:

- a) GaN enhancement and depletion-mode discrete power devices [3];
- b) GaN integrated power solutions;
- c) the above in wafer and package levels.

The prescribed test methods can be used for device characterization, production testing, reliability evaluations and application assessments of GaN power conversion devices. This document is not intended to cover the underlying mechanisms of dynamic ON-resistance and its symbolic representation for product specifications.

2 Normative references Teh STANDARD

There are no normative references in this document.

3 Terms, definitions, symbols and abbreviated terms)

3.1 Terms and definitions

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- IEC Electropedia: available at http://www.electropedia.org/
- ISO Online browsing platform: available at http://www.iso.org/obp

3.2 Symbols and abbreviated terms

Symbol or abbreviation	Name or term
DUT	Device Under Test
V _{DD}	Supply voltage
V _{DS}	Drain to Source Voltage of DUT
V _{GS}	Gate to Source Voltage of DUT
D1	Free-wheeling diode
L	Inductance
R	Resistance
С	Capacitance
ID	Drain current of DUT in ON-state
V _{DS(ON)}	Drain to Source Voltage of DUT in ON-state
R _{DS(ON)}	Drain to Source Resistance of DUT in ON-state